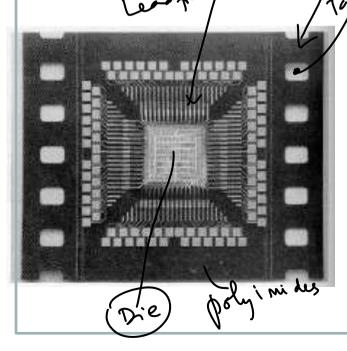
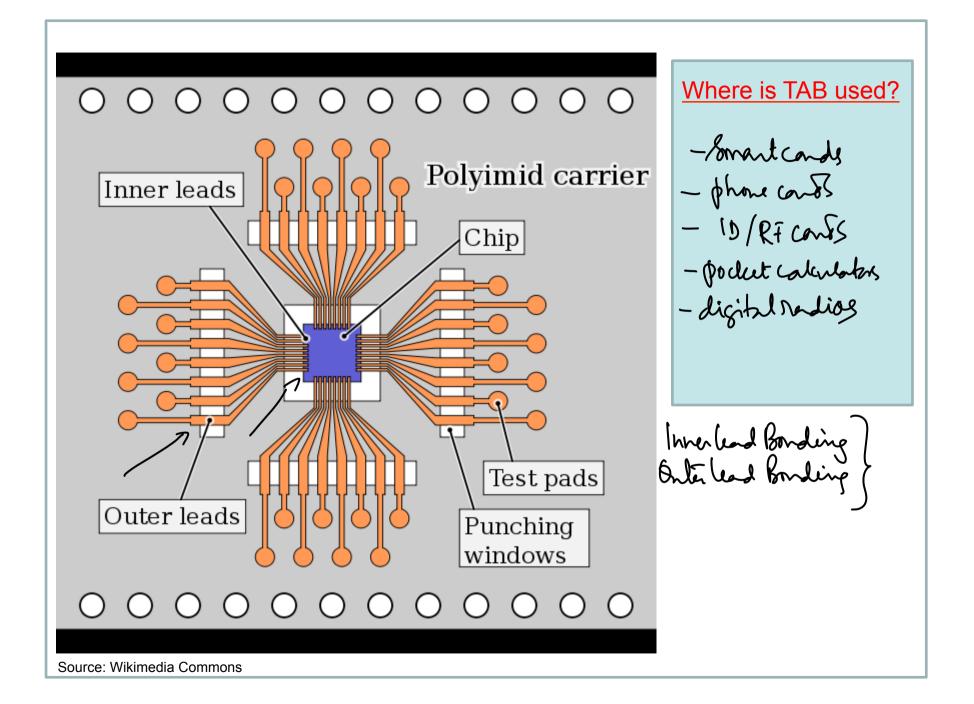


TAB (Tape Automated Bonding)

- Interconnect Patterned On Tape
- Stronger Lead Bonding Strength
- Supports Smaller On-chip Pin Size and Pitch
- Supports upto 850 pins
- Better Electrical Performance than Wire bonds

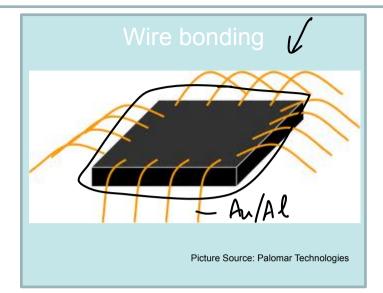


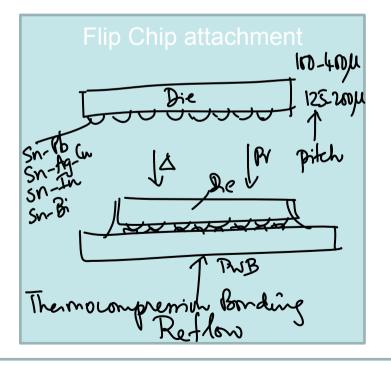
TAB is an approach to fine the pitch interconnection of a chip to a lead frame. The interconnections are patterned on a multi layer polymer tape. The tape is positioned above the 'bare die' so that the metal tracks (on the polymer tape) correspond to the bonding sites on the die. Welding is done by thermocompression bonding.

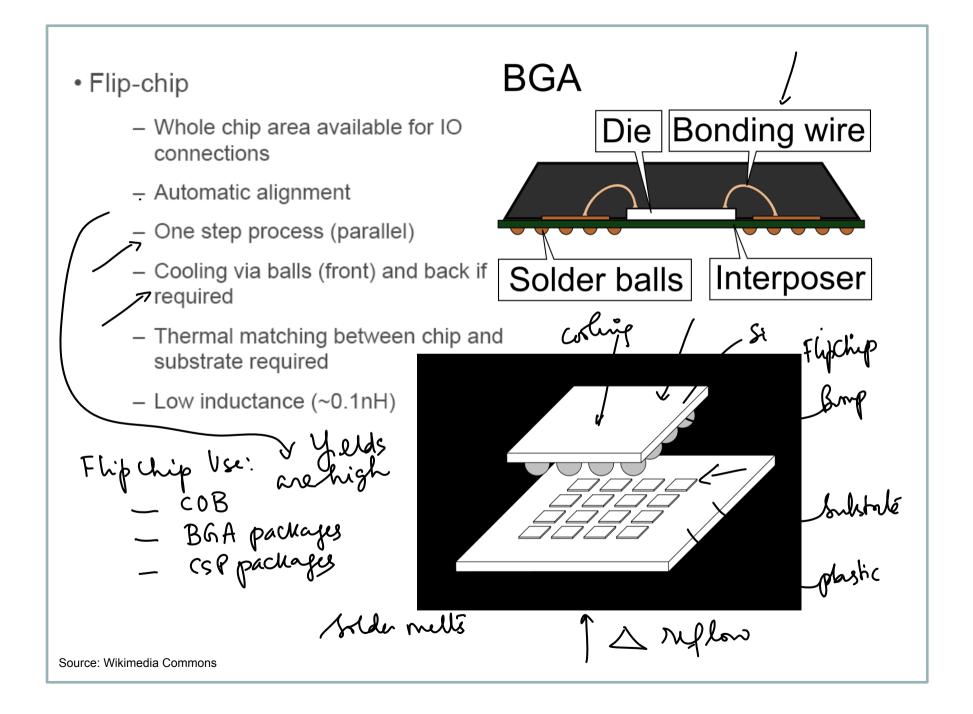


Flip-Chip (C4) Attachment

- What is Flip-Chip?
 - A method to electrically connect the die to the package carrier
 - The bond wire is replaced with a conductive "bump" placed directly on the die surface
 - Under-fill epoxy is used to secure the attachment and absorb stress
 - The chip is then "flipped" face down onto the package carrier using a reflow process
 - Bump sizes range from 90-125 microns in diameter
 - Also known as C4 (Controlled Collapsible Chip Connection)
 - Invented by IBM in 1963







Flip Chip

- Flip-Chip is :
 - NOT a Specific Substrate material
 - NOT a Specific Package like SOIC

-> digital cameras -> Camenders -> laptop -> Comm/handhillproducts

NOT a Specific Package Type like QFP, BGA or PGA

) (OB

Can be mounted on organic and ceramic substrates; in other words- at board level too

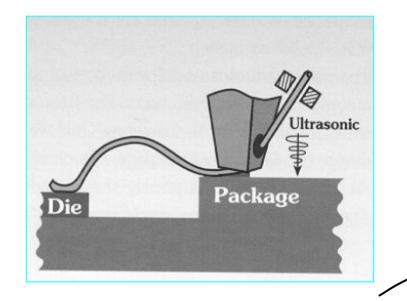
Summary of first level connection choices Next up: Description of Wirebonding, TAB and C4 processes



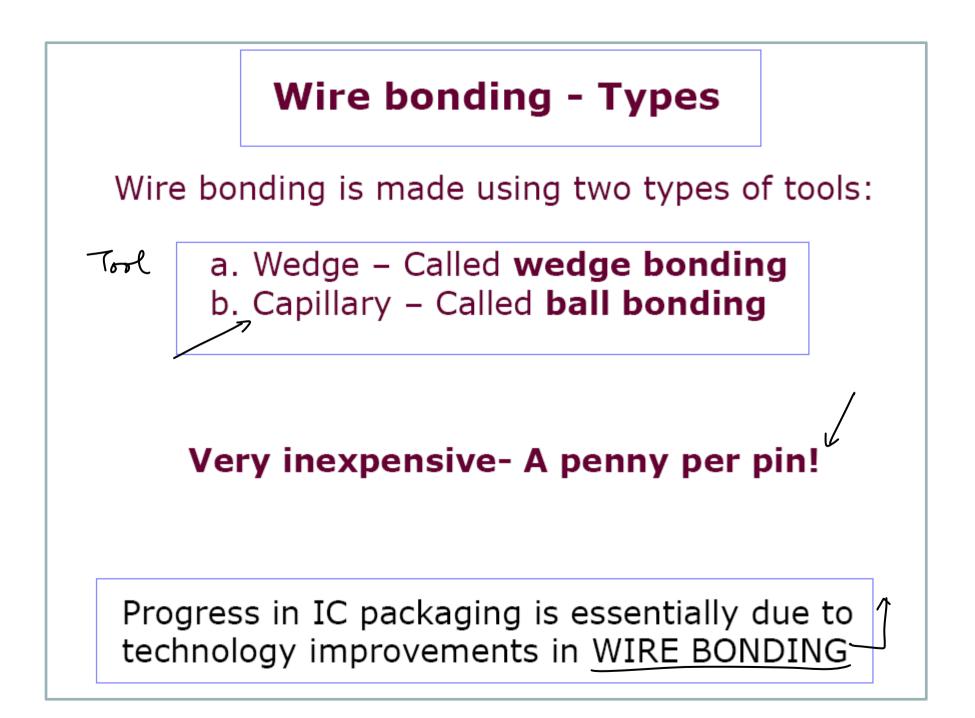
Wire Bonding

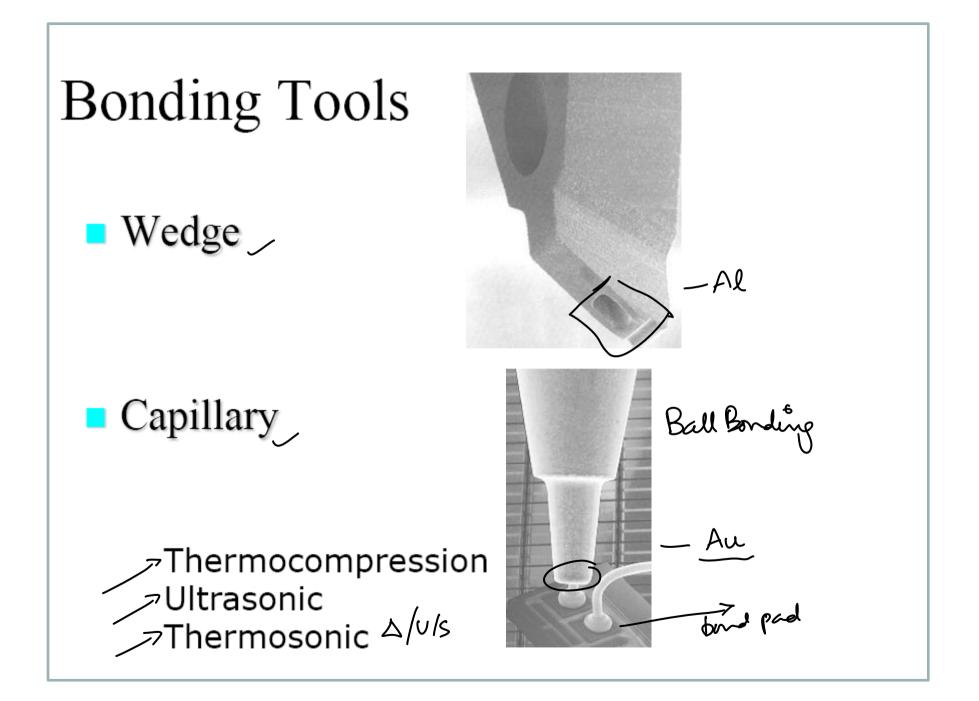
Used in interconnecting the Die to various substrates

...the most popular interconnection method



Wire bonding is a **SOLID phase welding process** where the two metallic materials, **a thin wire** and the metallization on **pad surface** are brought into intimate contact under a **combination of heat, pressure, and/or ultrasonic energy...**





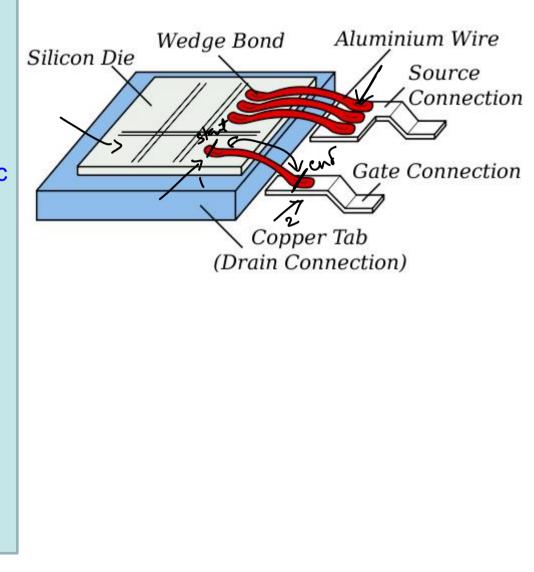
Al is more suited for wedge bonding

A

Process Steps

Wedge tool loaded with wire
Apply pressure and ultrasonic
energy to form wedge (chip)
Bonding on substrate pad
Loop formation
Package bond pad formation
Wire break-off to finish
process

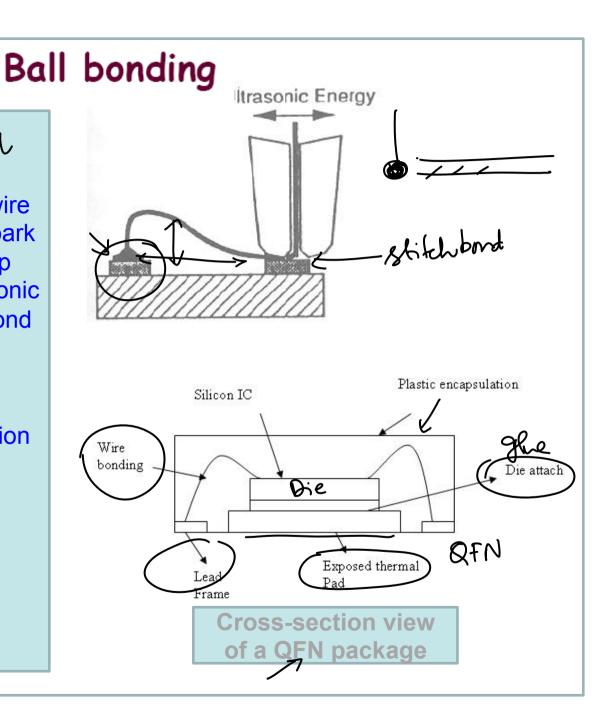
Source: Wikimedia Commons



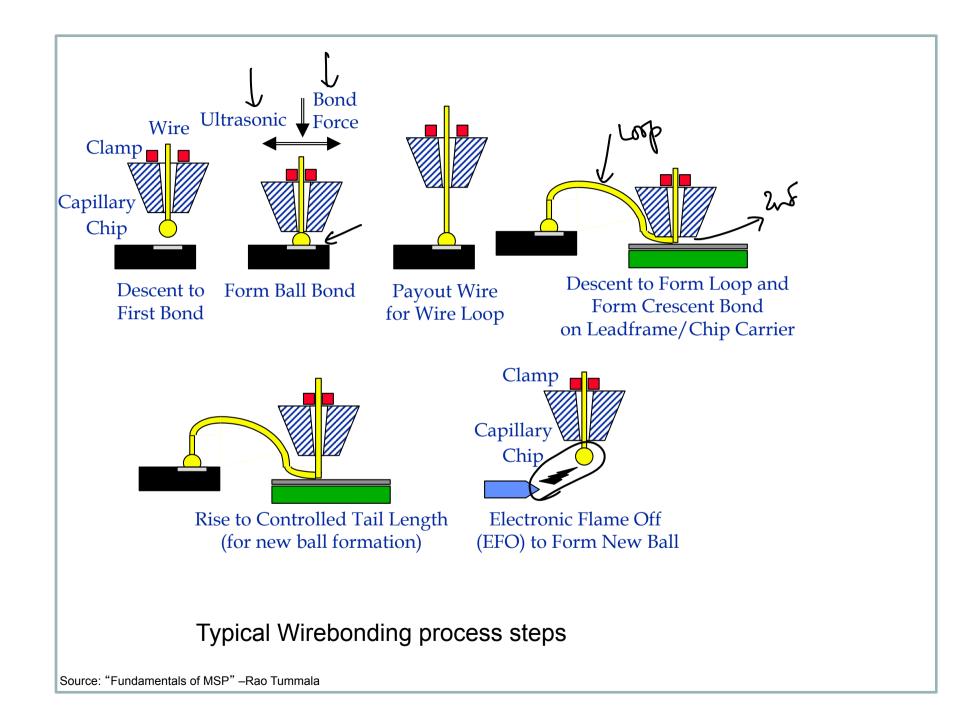
Process Steps

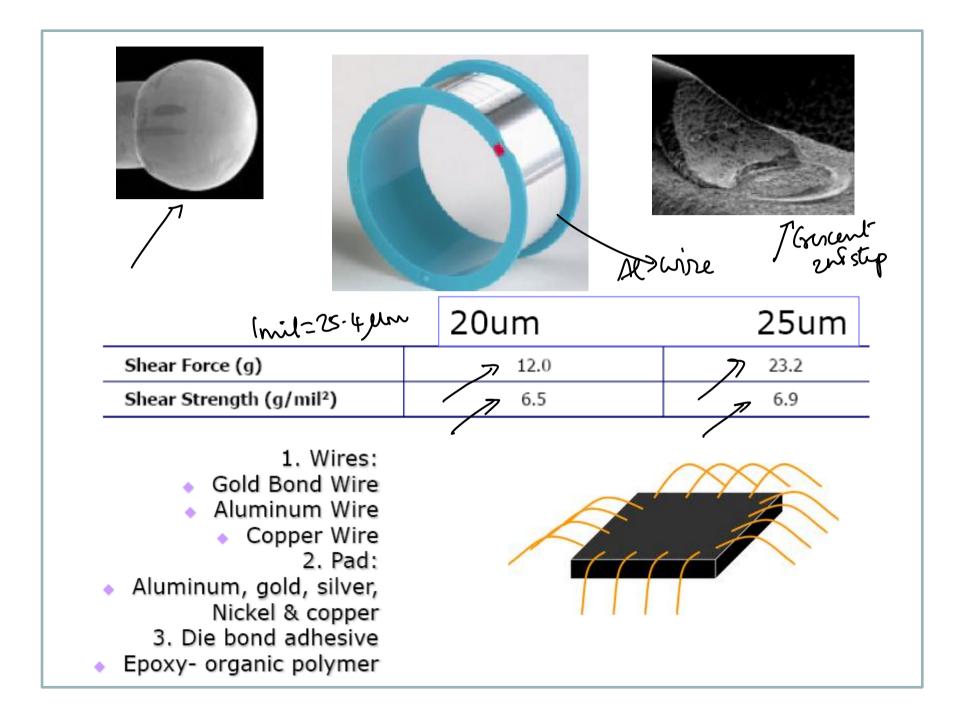


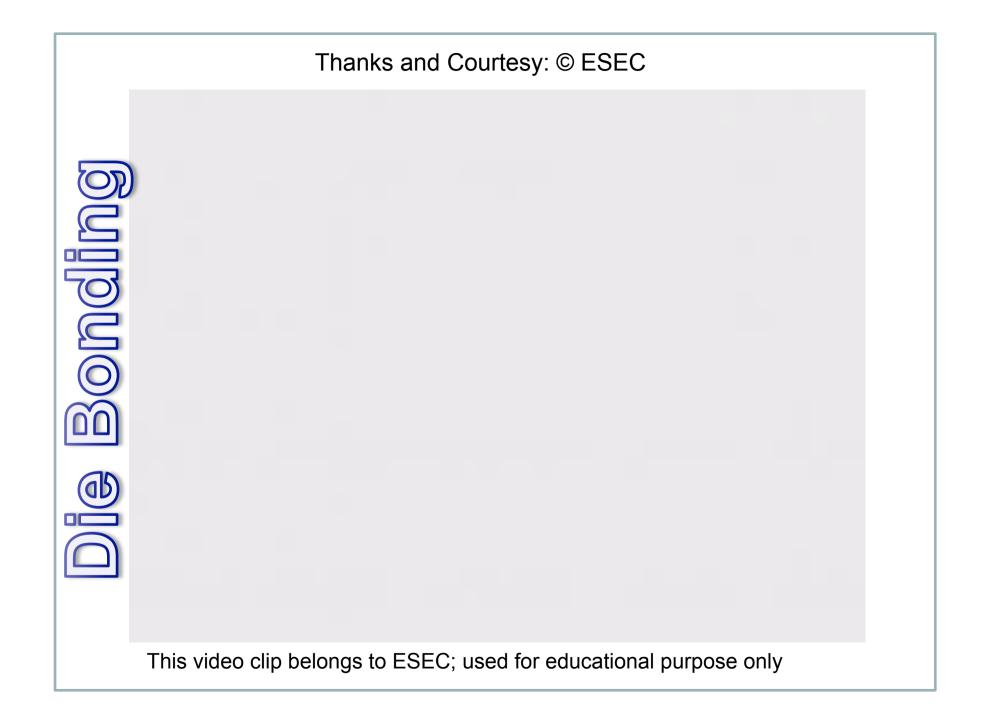
Capillary loaded with Au wire
EFO wand generates a spark to melt the Au wire at the tip
Apply pressure and ultrasonic energy, heat to form ball bond at bond pad on chip side
Bonding on substrate pad
Loop formation
Package bond pad formation by stitch bonding
Wire break-off to finish process



Source: Wikimedia Commons











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Features of Wire bonding methods

- High speed (bonding time 40ms:2-4 wires/sec)
- Economical
- Strong bond
- Larger Bonding Pad
 - (2 mil gold wire: 5*5mil pad)
- Ultrasonic can be used for Al wires
- Thermosonic works at 150 C- faster bond time

Comparison of three methods

Wirebonding	Pressure	Temperature	Ultrasonic energy	Wire	Pad
Thermo- compression	High	300-500 °C	No	Au	Al, Au
Ultrasonic	Low	<80 °C	Yes	AI	Al, Au
Thermosonic	Low	100-150 °C	Yes	Au	Al, Au

1. Bond Failure

- Wirebond fatigue (temp cycling)
- Interdiffusion (impurities)
- 2. Wire failure
 - Wire flexure
 - Vibration fatigue
 - Axial fatigue
- 3. Corrosion
- 4. Intermetallic growth properties

Au-Be; Al-Si/Mg; Cu-Al..

Testing 1. Bond failure Ball bond shear test Destructive pull test 2. Wire failure Random vibration Accelerated tests as per standards HAST Mechanical shock 3. Testing for Corrosion